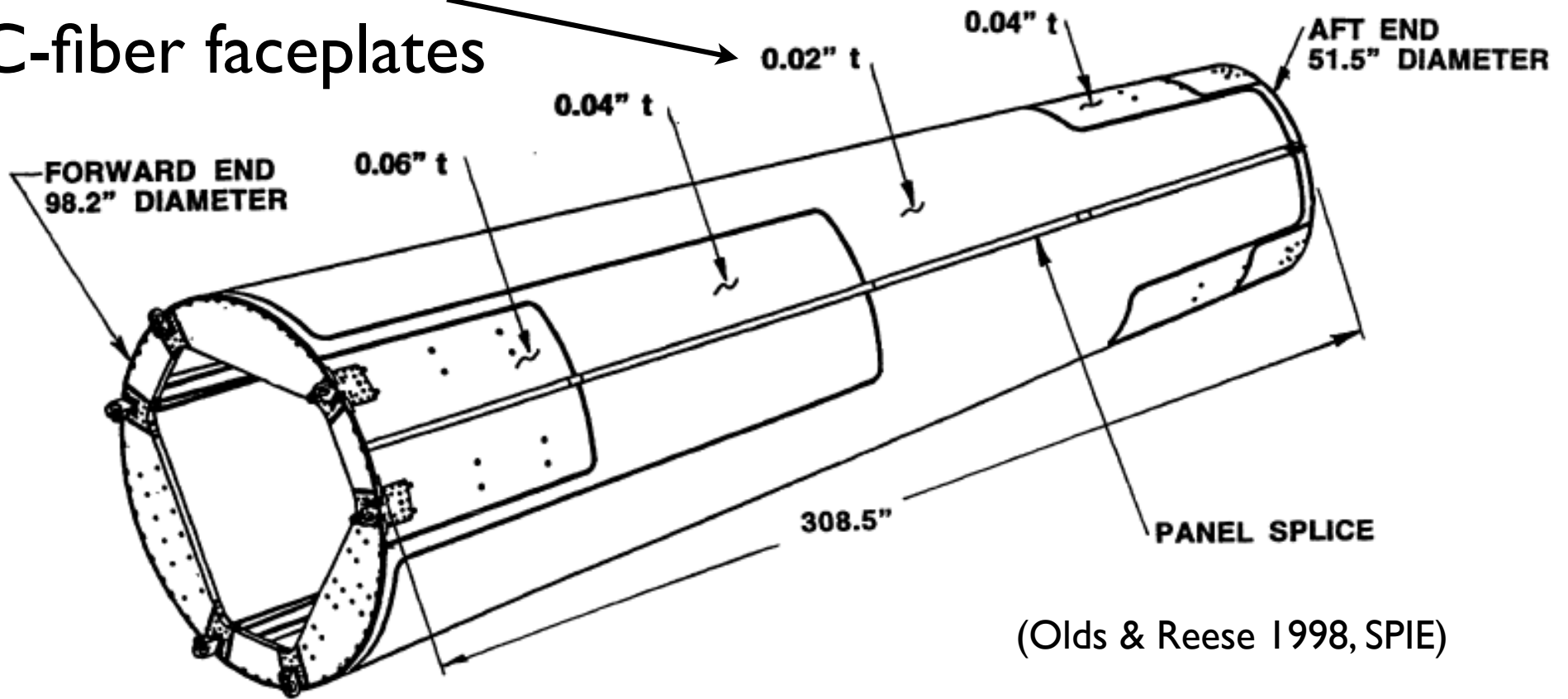


# Chandra Optical Bench

thicknesses of  
C-fiber faceplates



(Olds & Reese 1998, SPIE)

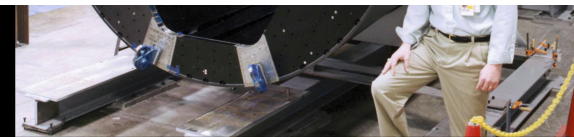
Figure 2.2-1 Optical bench.



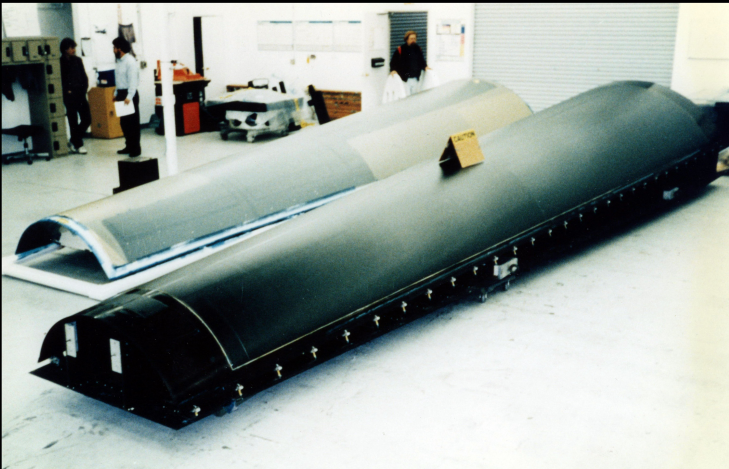
Optical Bench during initial assembly at ITT



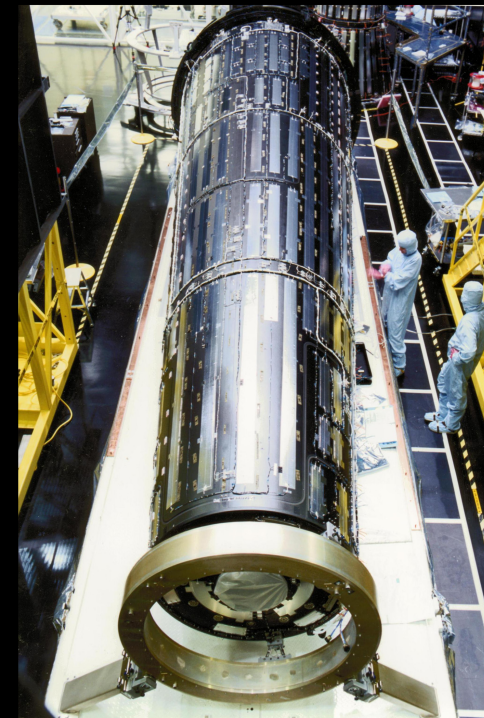
Structure being prepared for Static Load Test in Handling Fixture



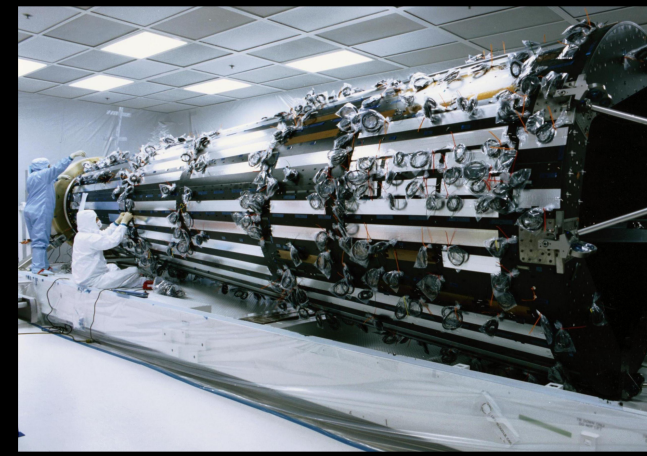
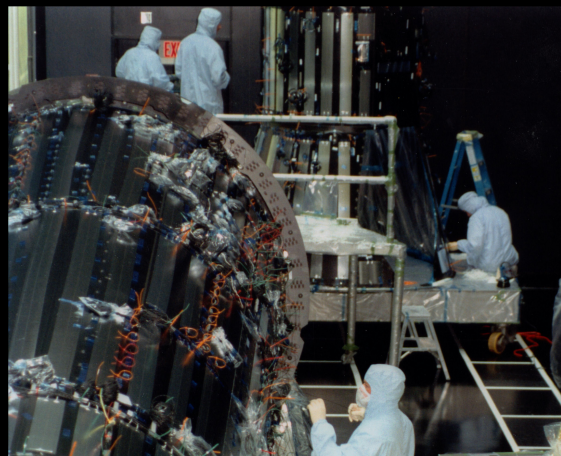
OBA during electrical assembly operations



Optical Bench Structure during Static Load Testing at ITT

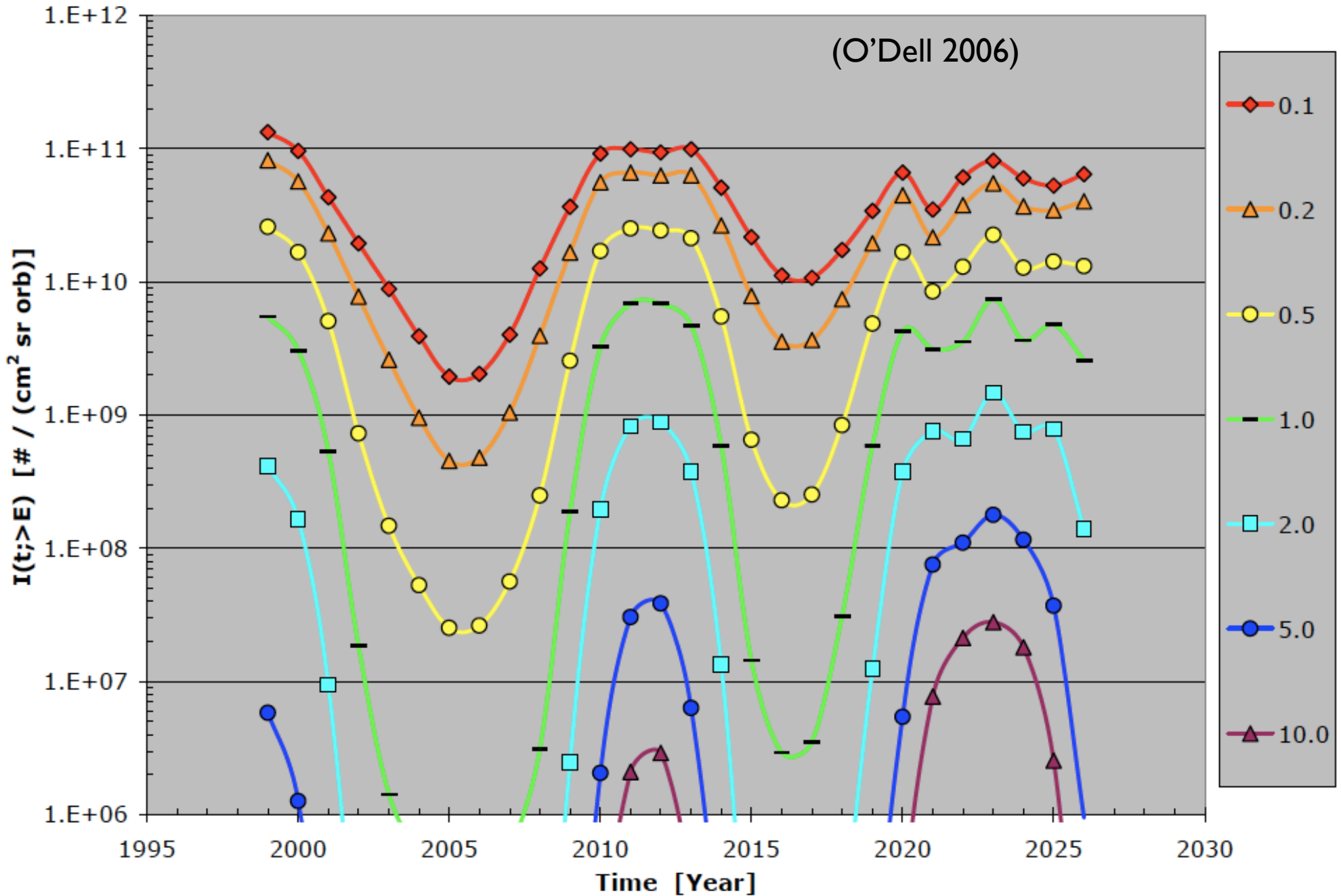


Completed OBA with blankets installed being prepared for HRMA integration at NGAS



# Trapped-proton intensity

(O'Dell 2006)



# Proton Sputtering?

- $dN_c/dt \sim 10^{19-22}$  atoms/yr in contaminant
  - minimum = only on filter
  - maximum = 0.1% on filter, rest vents or elsewhere
- Trapped proton fluxes  $\sim 200-10^7$  p/cm<sup>2</sup>/s/sr
  - minimum at 10 MeV, max at 100 keV
- At  $E \sim 10$  MeV, p penetrates 1 mm C-fiber
  - $dn/dt$  at 10 MeV:  $10^{16}$  p/yr
  - $E < 500$  keV  $\rightarrow$  cascading sputter,  $>2 \times 10^{20}$  atom/yr